## INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket number (Optional)	Application Number		
15689.49.5	10/673,658		
Applicant(s)			
Takehi	ro Nakamura et al.		
Takehi Filing Date	ro Nakamura et al.  Group Art Unit		

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	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	YES	slation NO
	1	0 682 418 A2	05/12/1995	EPO	H0487	005	X	
	2	CN1126930	7/17/1996	China	H04B7	005	X	
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## INFORMATION DISCLOSURE CITATION

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Docket number (Optional) 15689.49.5	Application Number 10/673,658			
	10/0/3,030			
Applicant(s)				
Takehi	ro Nakamura et al.			
Filing Date	Group Art Unit			

*Examiner Initial	OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
	3	Chinese Office Action for Chinese Patent Application No.: 20031010330.1	
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EXAMINER		DATE CONSIDERED	
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